

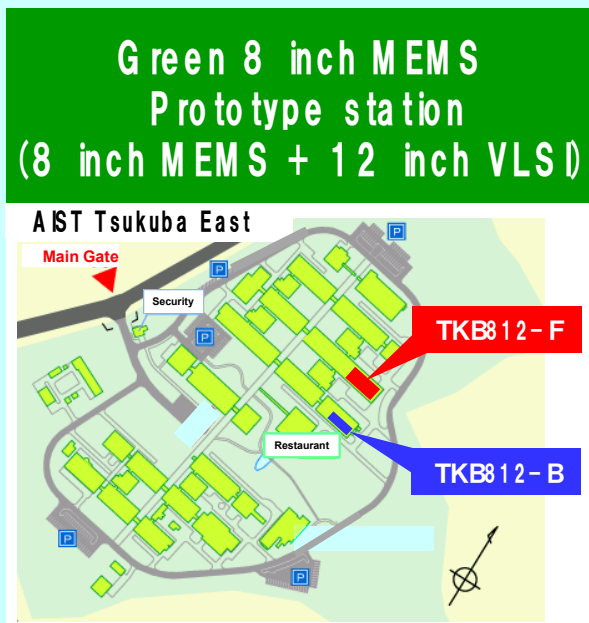
# Green 8 inch MEMS prototype station "TKB812"

## G Device Center, BEANS Laboratory

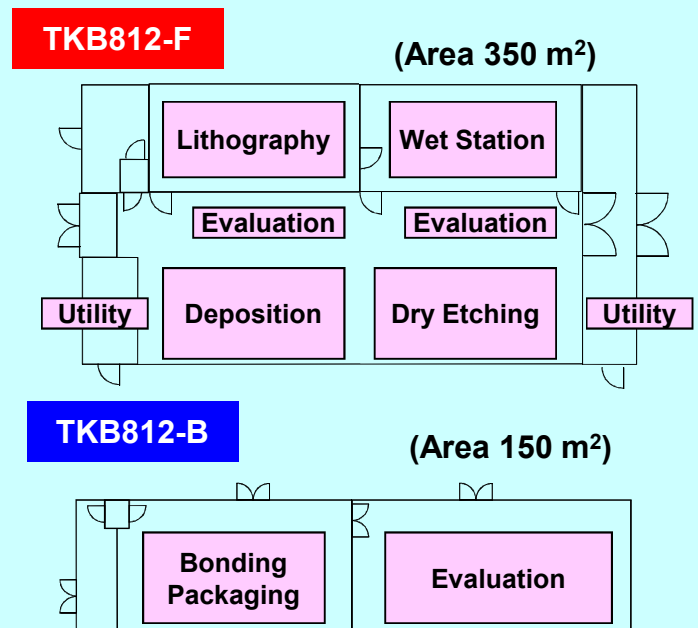
**Keywords: MEMS, micromachining, sensor network**

### Abstract

- ◆ "TKB812", wafer processing / packaging and evaluation line
- ◆ Smart clean room by sensor network system monitoring



**Fig. 1. Location of TKB812**



**Fig. 2. Layouts of TKB812**



**Fig. 3. Process and evaluation equipments**